

***DETAILED ACTION***

***Supplemental Examiner's Amendment***

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Mr. Paul, Chester M on 7/3/09, (Reg # 51,990).

The application has been amended as follows:

**IN THE CLAIMS:**

Claim 1, (Currently Amended) A computer-based method for teaching a knowledge-based database for automatic defect classification, which comprises:

- (a) accepting, using a specially programmed computer, a user selection of a review data file;
- (b) accepting, using the specially programmed computer, parameters and data input by a user on one page of a learning mode whereby the parameters and the data are known to the user;
- (c) starting, using the specially programmed computer, an alignment procedure and a procedure for adjusting light intensity, the alignment procedure with respect to at least one point on a wafer;
- (d) automatically adjusting, using the specially programmed computer, the optimal intensity of the light intensity accepting a selection of a first specific number of defects to

Art Unit: 2624

approach on a first wafer and taking respective pictures of the first specific number of defects on the first wafer and if necessary regulating to the optimal illumination using the respective pictures;

(e) checking, using the specially programmed computer, a detection, whereby an optimization of the detection parameters is carried out by accepting a selection of a second specific number of defects to approach on a second wafer, taking pictures of the second specific number of defects on the second wafer, displaying the pictures, and using the pictures to adjust a detection threshold;

(f) automatically approaching all defects of a wafer or wafers, whereby the respective defect is detected and a descriptor is assigned, by the specially programmed computer, to the respective defect; and,

(g) analyzing and automatically grouping, using the specially programmed computer, the descriptors of the defect.

***Contact Information***

2. Any inquiry concerning this communication or earlier communications from the examiner should be directed to SHEELA C. CHAWAN whose telephone number is (571)272-7446. The examiner can normally be reached on 7.30- 5.00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Vikkram Bali can be reached on 571-272-7401. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free)? If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Sheela C Chawan/

8/5/09

Primary Examiner, Art Unit 2624